

Notice of References Cited	Application/Control No. 09/832,867	Applicant(s)/Patent Under Reexamination YAMAZAKI ET AL.	
	Examiner Monica Lewis	Art Unit 2822	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,225,150	05-2001	Lee et al.	438/153
*	B	US-6,288,413	09-2001	Kamiura et al.	257/66
*	C	US-6,259,138	07-2001	Ohtani et al.	257/351
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NON-PATENT DOCUMENTS

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	V	S. Wolf, Silicon Processing, 1990, Lattice Press, Volume 2, Page 398.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.